

## Magnetoresistance and transport in carbon nanotube-based devices

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Schriften des Forschungszentrums Jülich  
Reihe Schlüsseltechnologien / Key Technologies

Band / Volume 78

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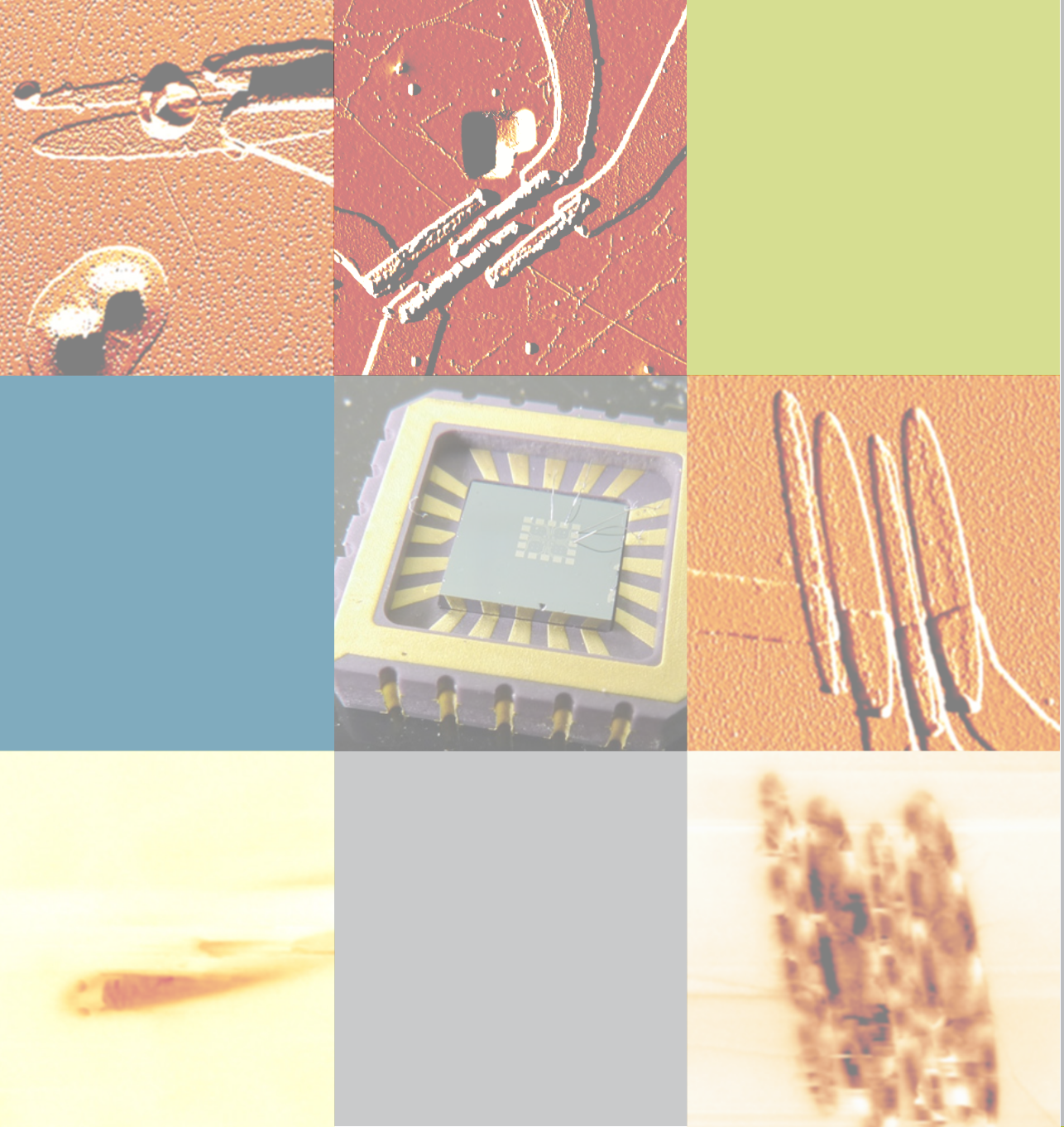
ISSN 1866-1807

ISBN 978-3-89336-926-3

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**Schlüsseltechnologien / Key Technologies**  
**Band / Volume 78**  
**ISBN 978-3-89336-926-3**